

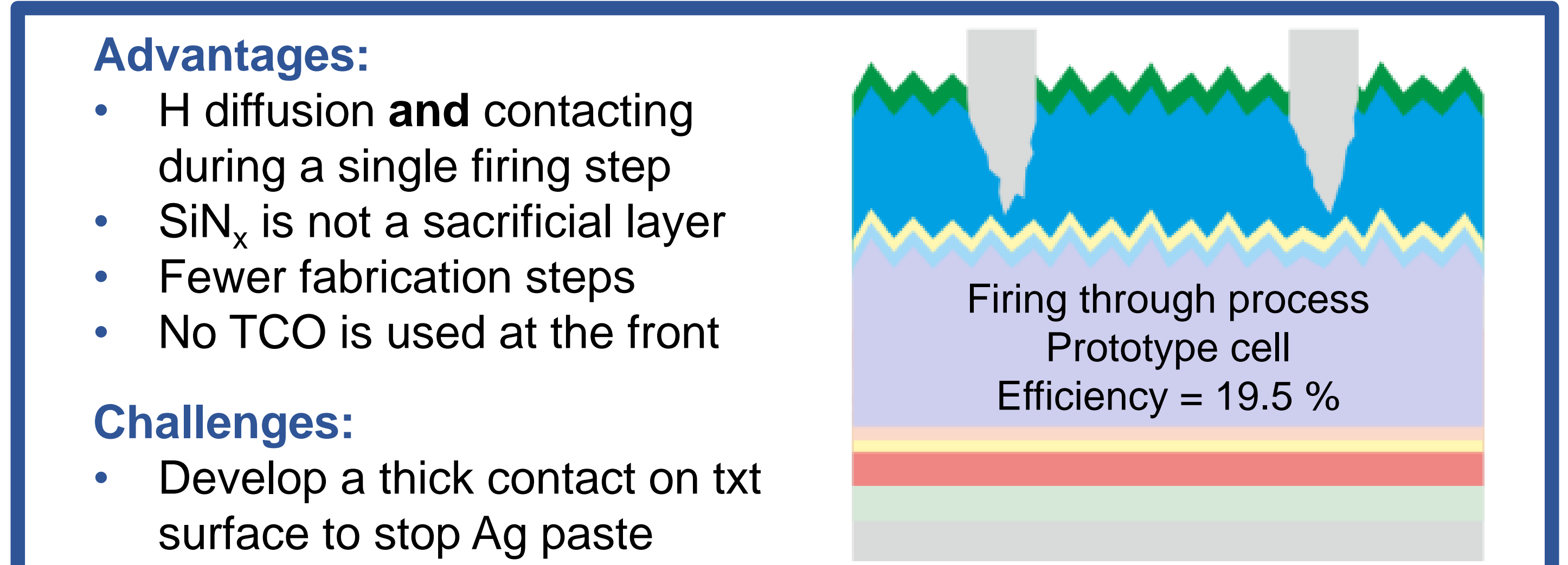
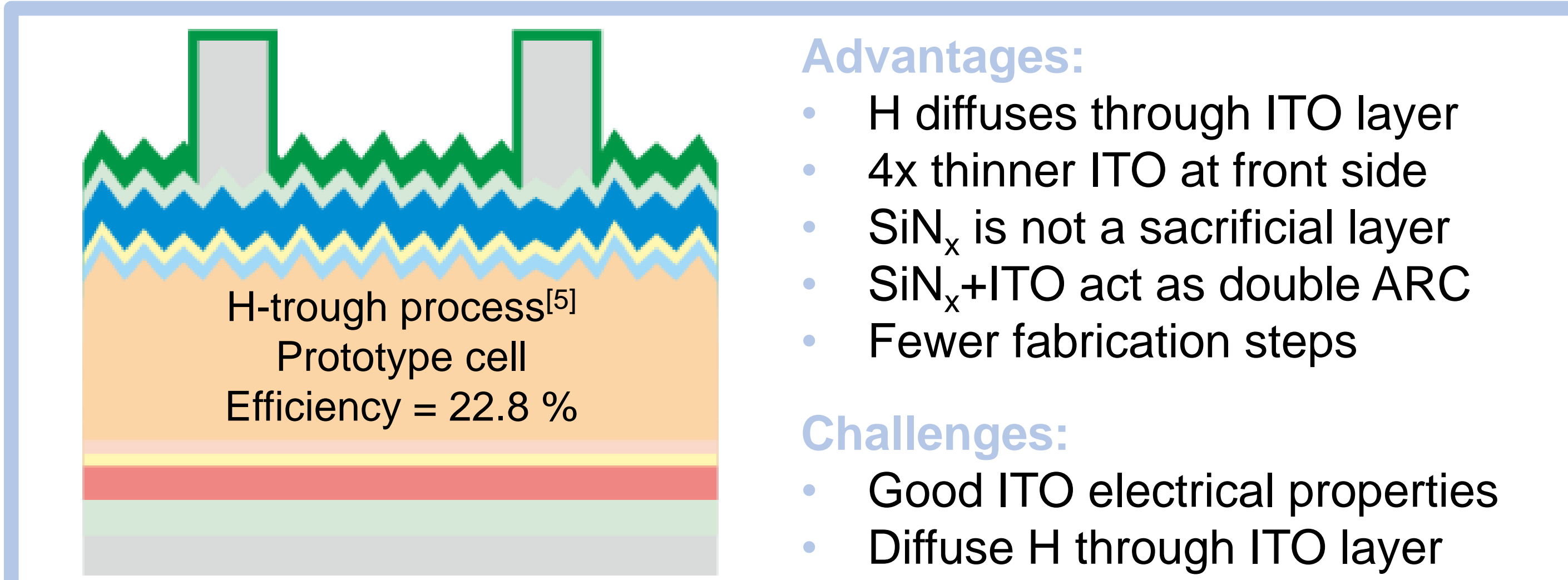
# Optimization of front contacting methods for high-efficiency c-Si solar cells with co-annealed passivating contacts

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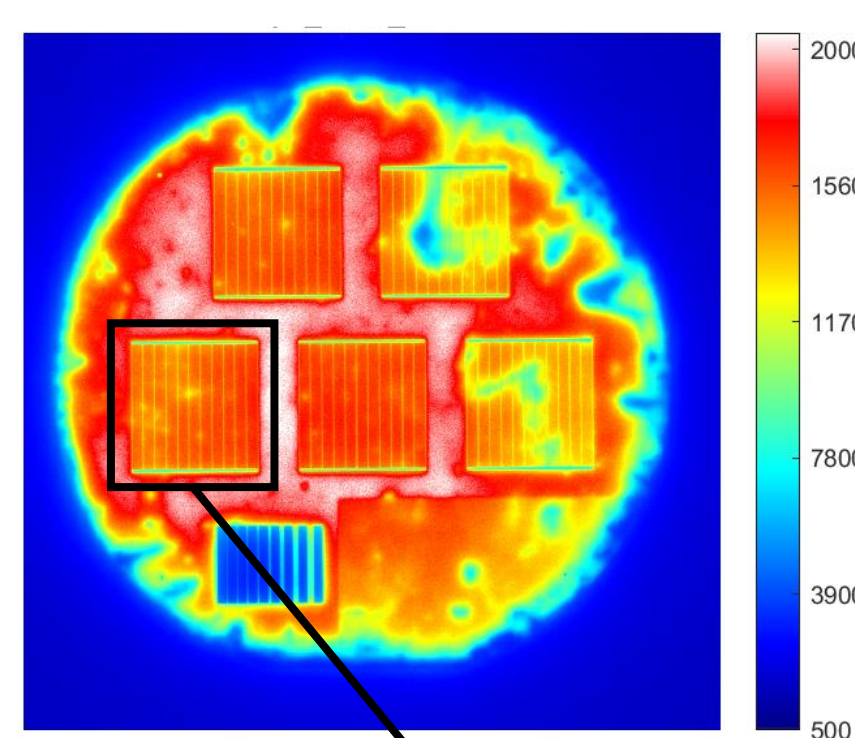
## Front contacting methods: PVLAB strategies

Passivating contacts are keys to enable conversion efficiency >25%<sup>[1,2]</sup> and are temperature tolerant. These contacts need an hydrogenation step<sup>[3,4]</sup>. Combining this step with industrial mainstream and avoiding the use of a sacrificial SiN<sub>x</sub> is a challenge.



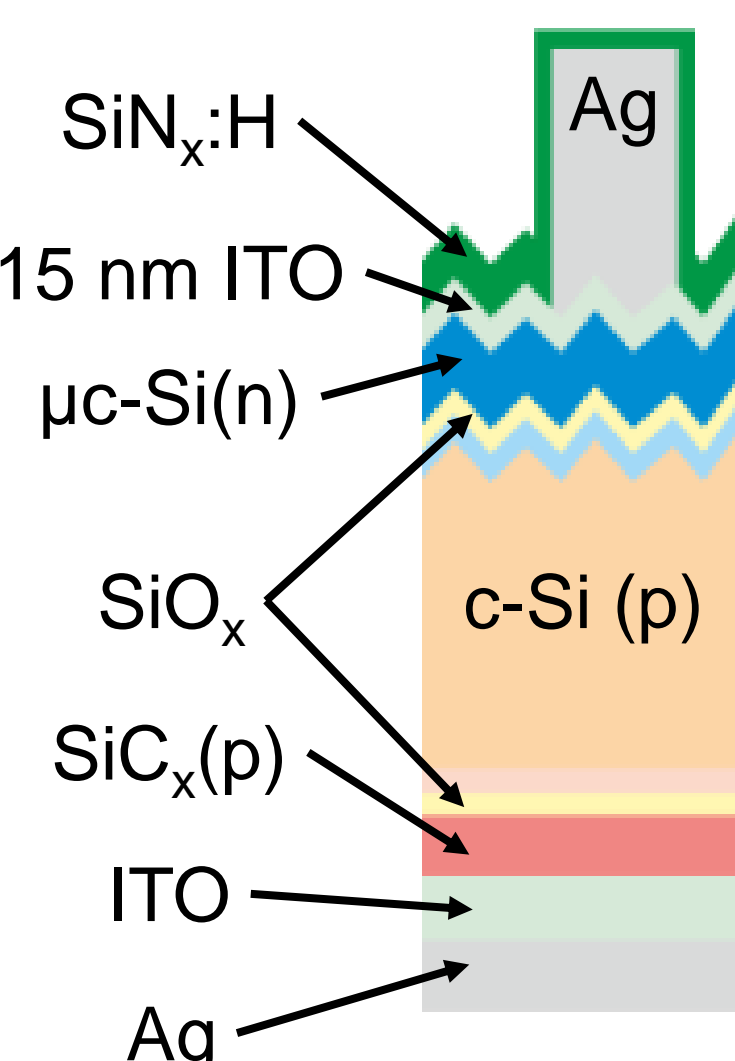
## H-through process

### PLI after hydrogenation

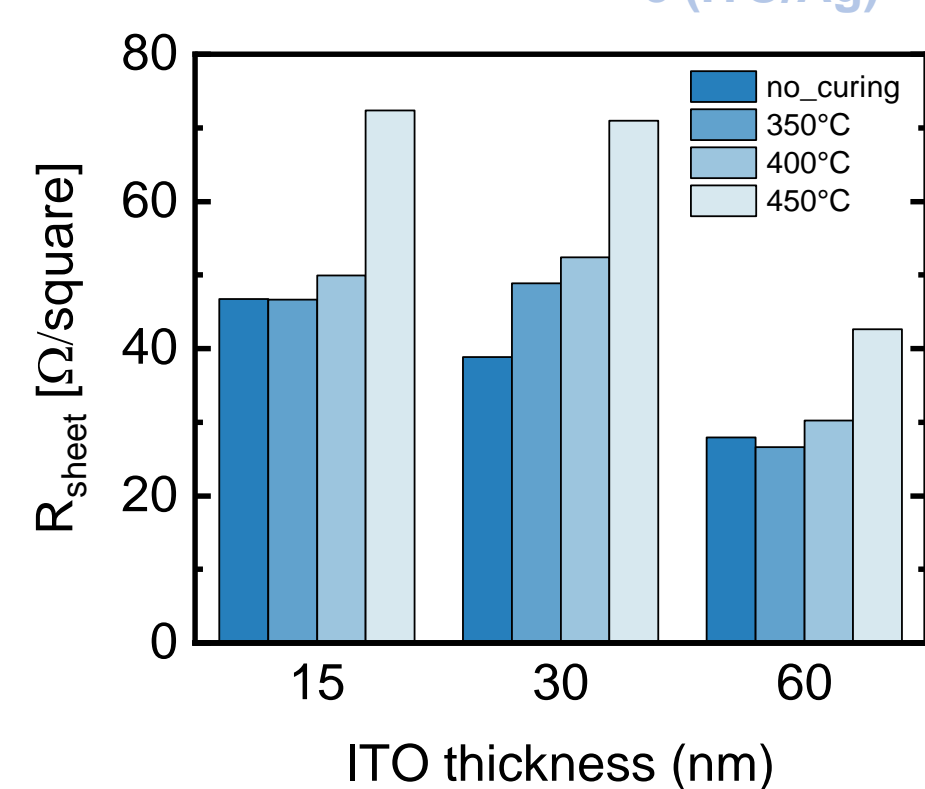
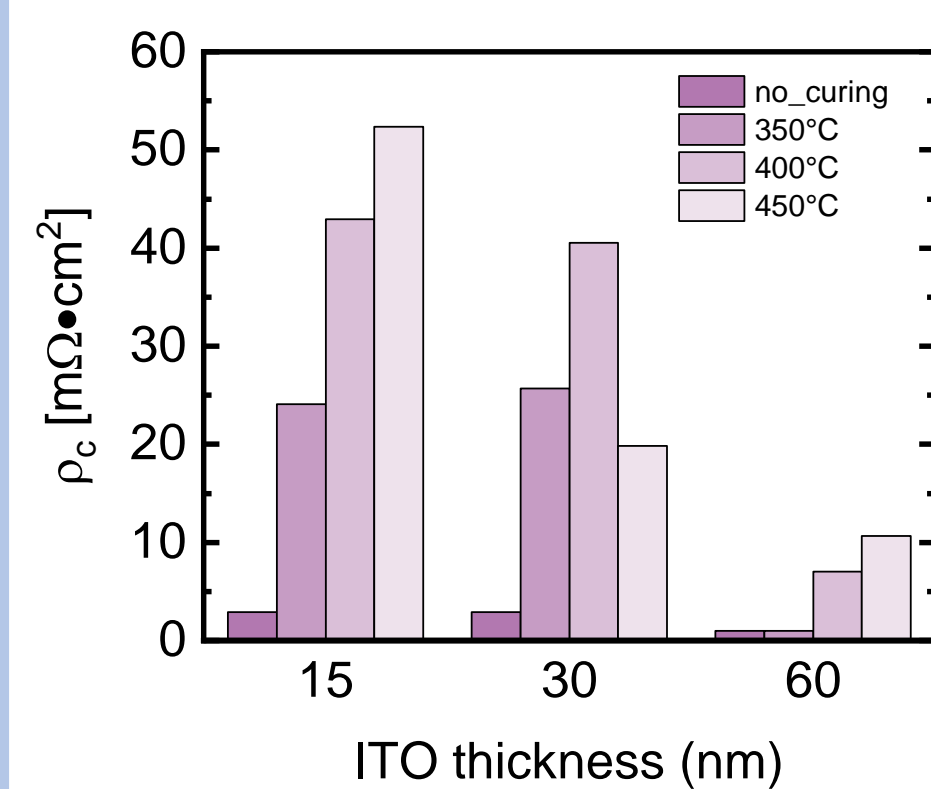


### Cell demonstrator:

- PECVD deposition of thin  $\mu\text{-Si(n)}$  (front) and  $\text{SiC(p)}$  (rear)
- Co-annealing at 850°C
- ITO sputtering, Ag printing and SiN<sub>x</sub> deposition (front)
- Annealing in N<sub>2</sub> atmosphere at 350°C for 30 min
- metallization with sputtered ITO/Ag stack at the rear



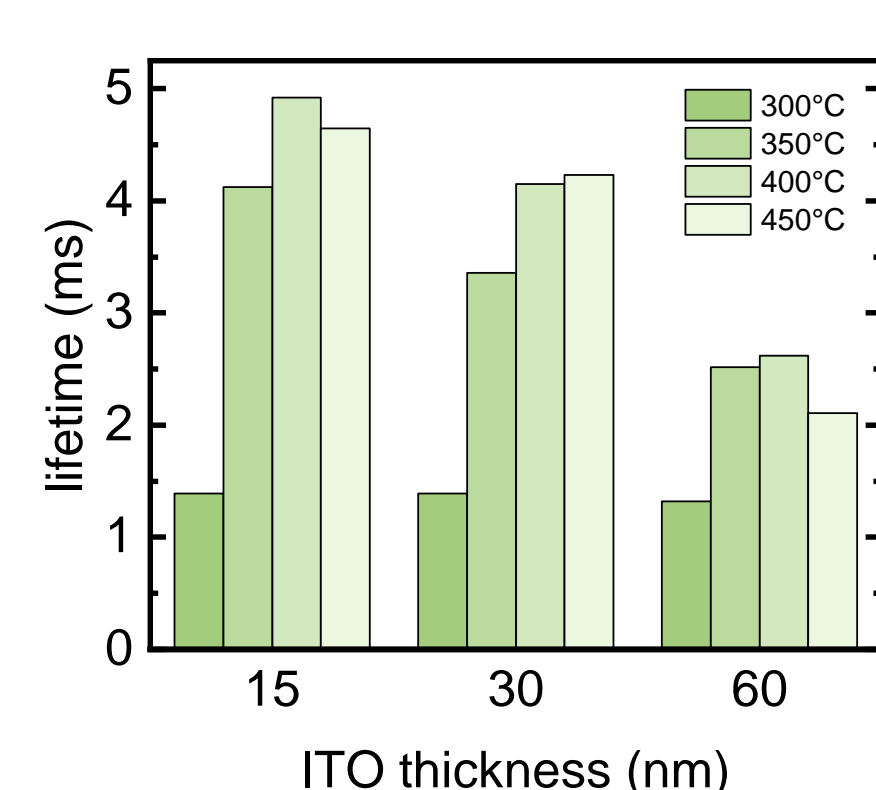
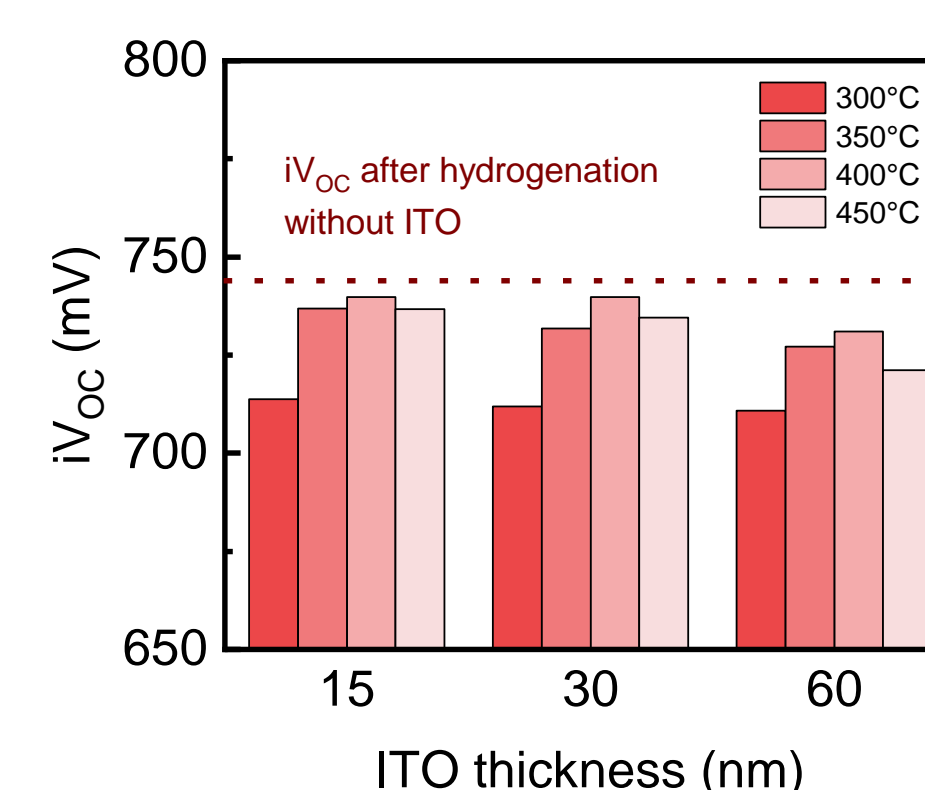
### Influence on the resistance ( $\rho_c$ (ITO/Ag) and $R_{\text{sheet}}$ (ITO))



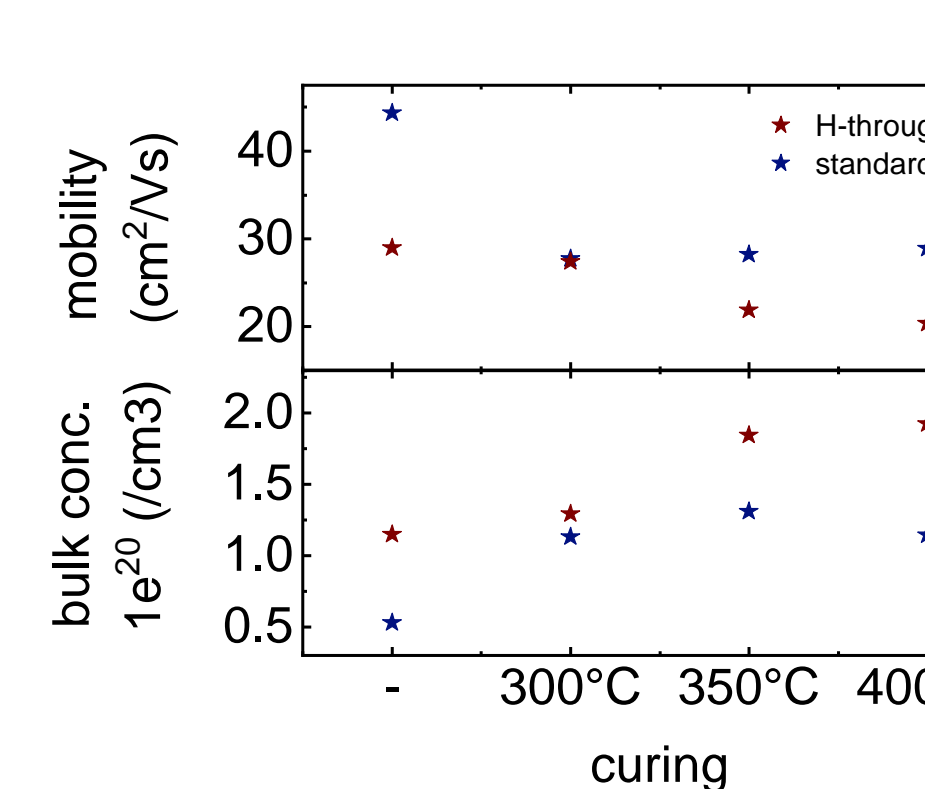
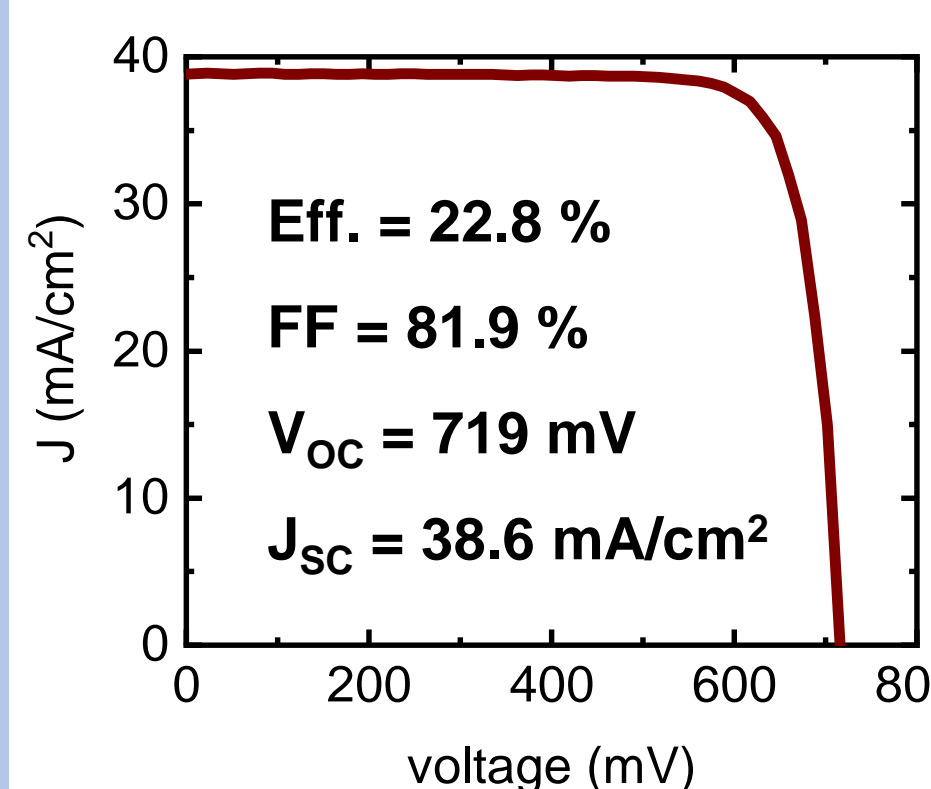
- $\rho_c < 60 \text{ m}\Omega\cdot\text{cm}^2$  for H-through process even with 15 nm of ITO
- Sheet res. < 80  $\Omega$ /square even at 450°C with 15 nm of ITO

### Feasibility of hydrogenation through the ITO layer

- High lifetime and  $iV_{\text{OC}}$
- Higher values obtained for thinner ITO layers
- Negligible  $iV_{\text{OC}}$  loss compared to hydrogenation without ITO



### Best cell and limitation



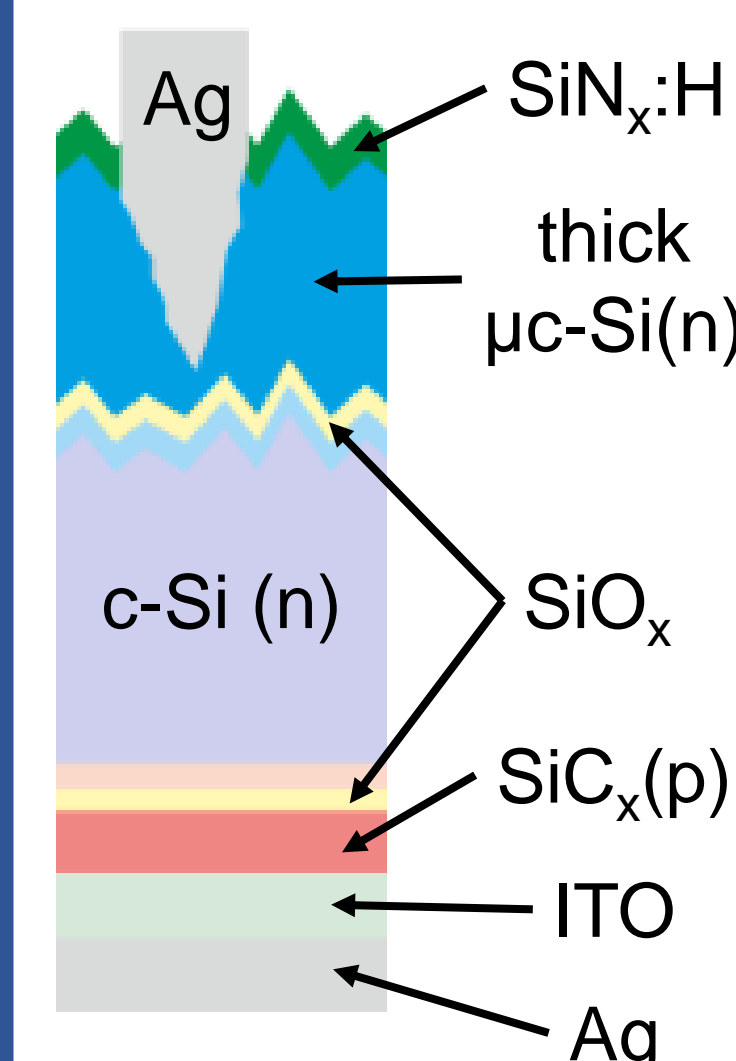
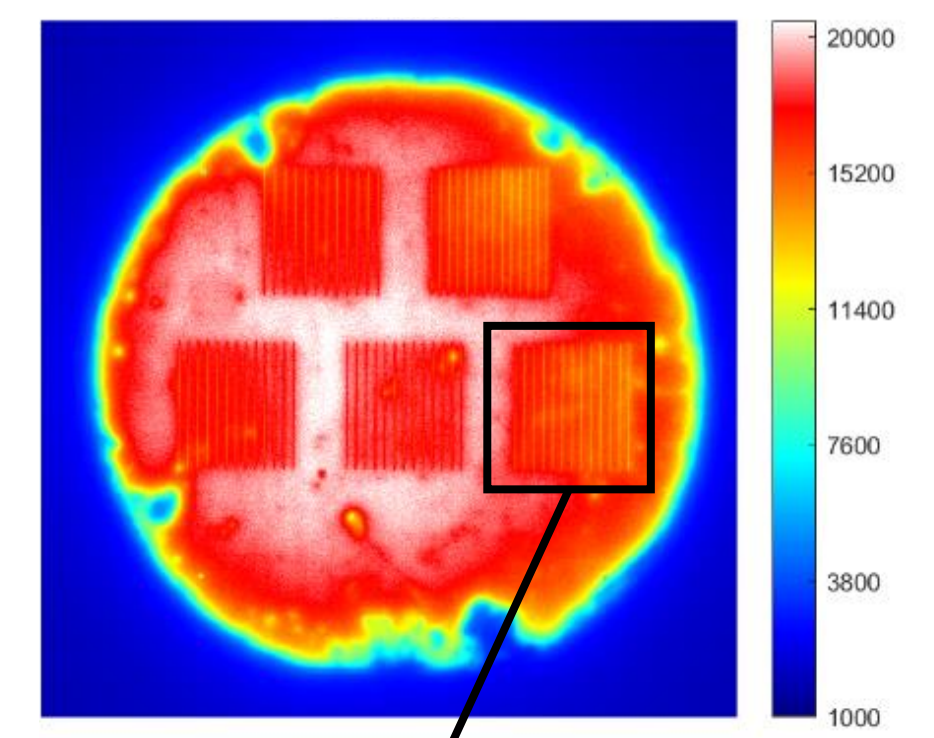
- Eff. limited by the current
- Current loss due to free carrier absorption in the near IR-region

## Firing through process

### Cell demonstrator:

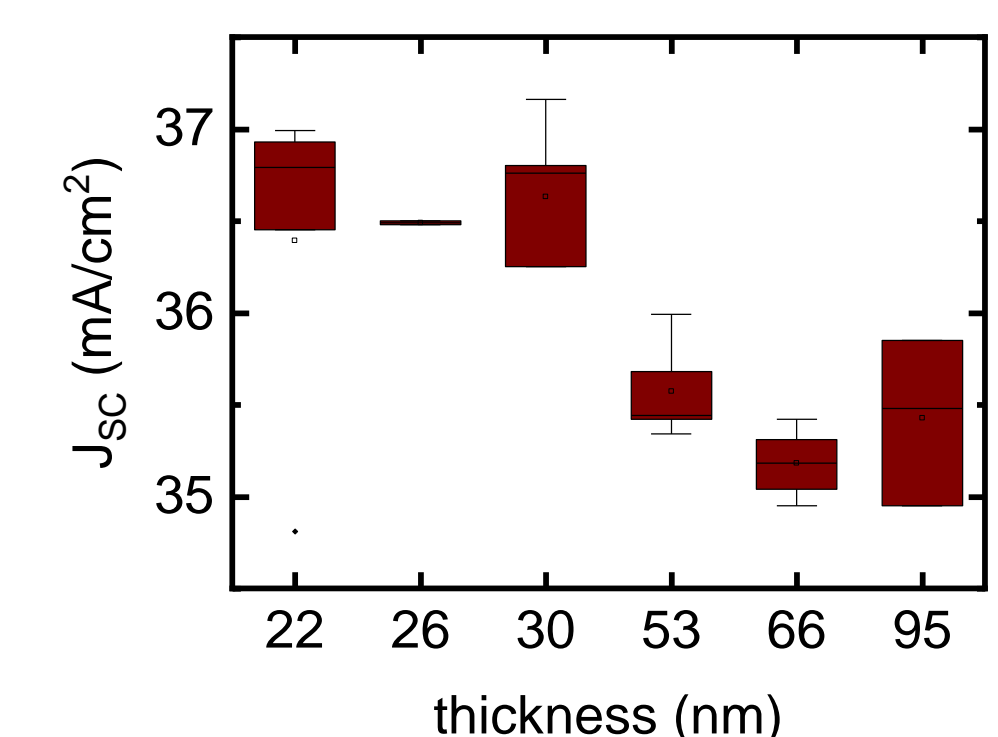
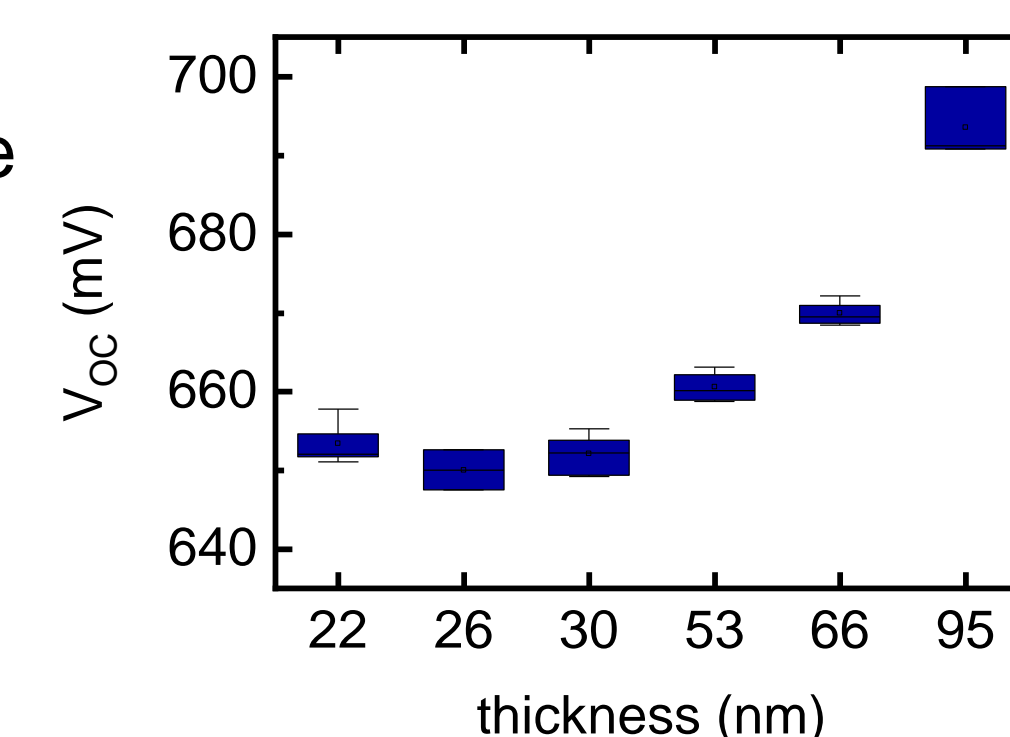
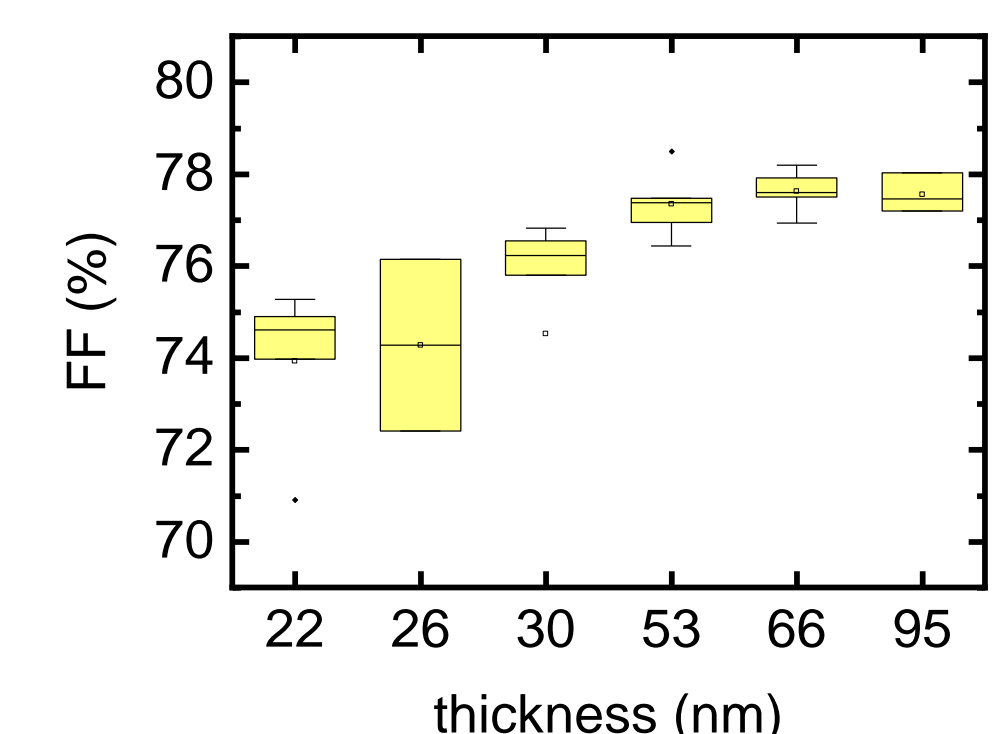
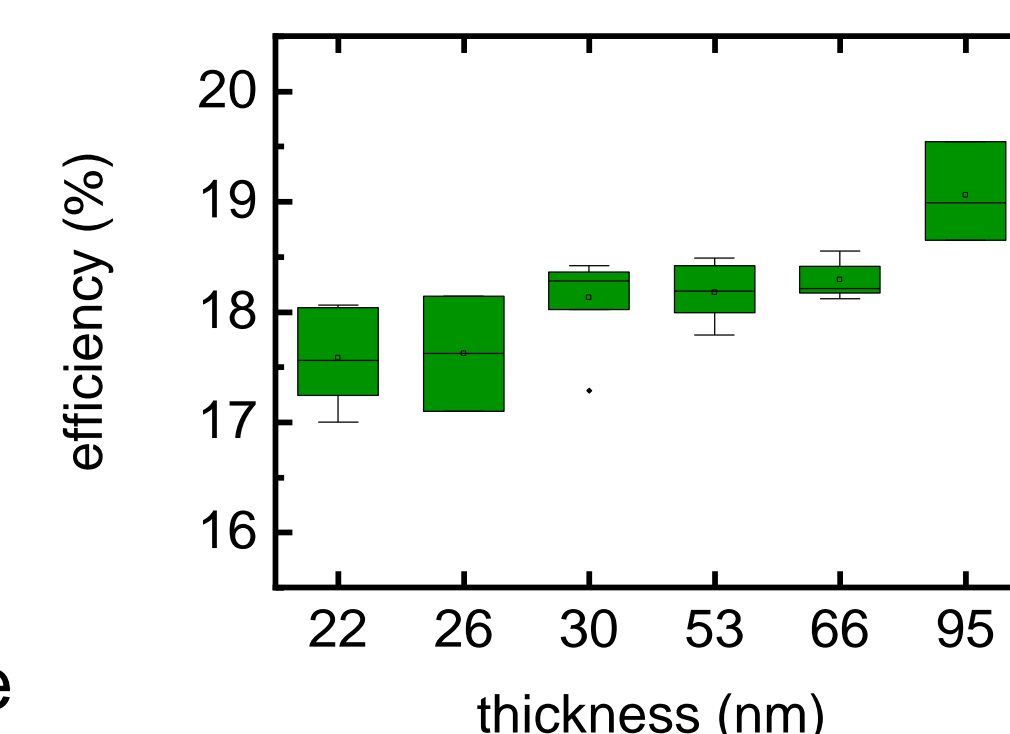
- PECVD deposition of thick  $\mu\text{-Si(n)}$  (front) and  $\text{SiC(p)}$  (rear)
- Co-annealing at 850°C
- SiN<sub>x</sub> deposition and Ag paste printing (front)
- Firing (hydrogenation and contacting of the Ag paste)
- metallization with sputtered ITO/Ag stack at the rear

### PLI after firing



### Influence of the front contact thickness on the cell parameters

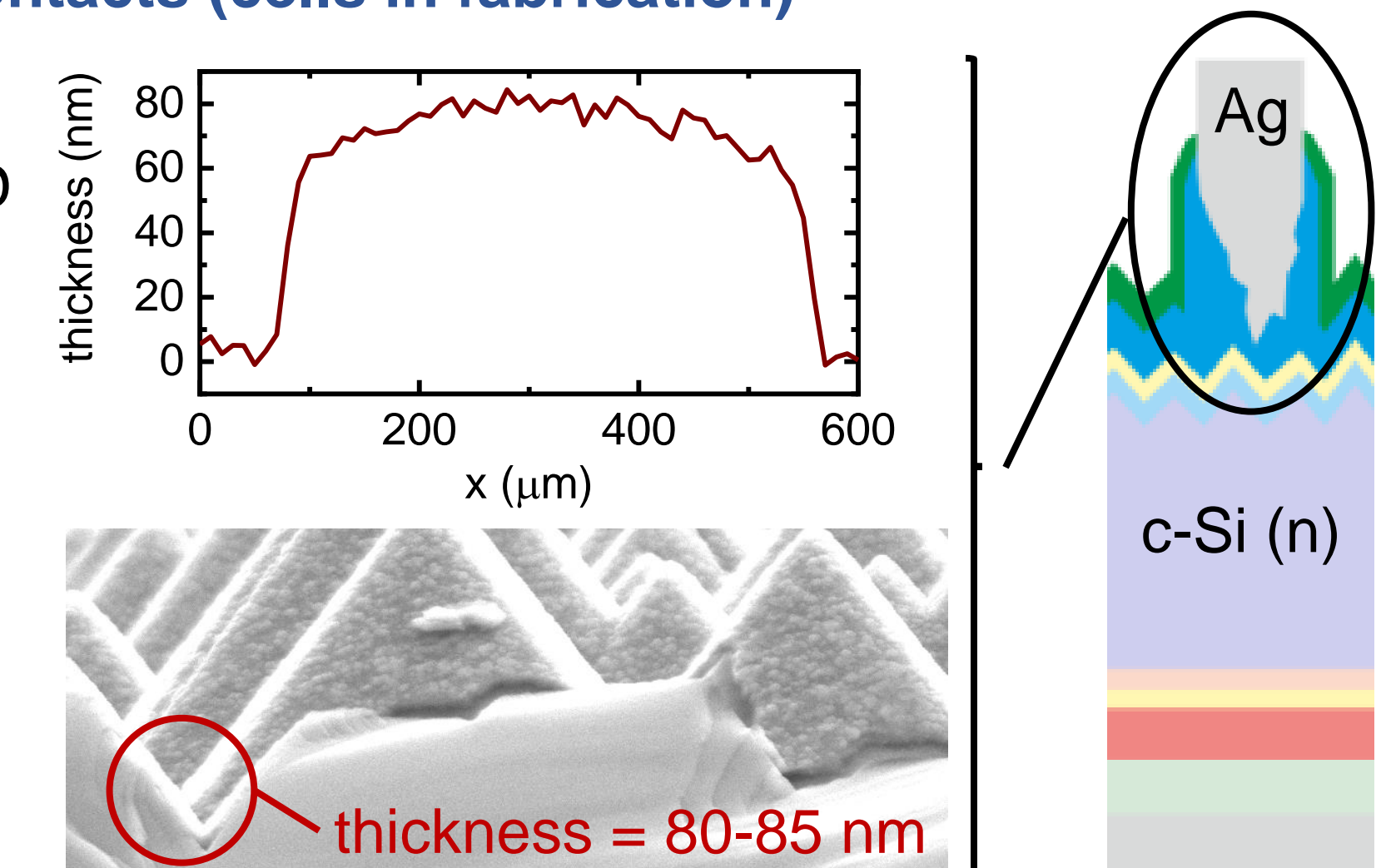
- Decrease of J<sub>SC</sub> → thick contacts are not fully transparent
- Increase in V<sub>OC</sub> → thick contacts can stop the Ag paste and protect the oxide
- FF quite constant → thick contacts ensure good current transport
- The efficiency is a trade-off between V<sub>OC</sub> or the J<sub>SC</sub>



### Localised contacts (cells in fabrication)

- Localization can be done by using a mask during the PECVD
- Loss in thickness due to the mask
- It can ensure high J<sub>SC</sub> and high V<sub>OC</sub> at the same time
- Predicted conversion efficiency:

Eff. = 22.2 %      FF = 78 %  
 V<sub>OC</sub> = 700 mV      J<sub>SC</sub> = 40.5 mA/cm<sup>2</sup>



## Conclusion

### H-through process:

- Demonstration of a SiN<sub>x</sub>/ITO stack enabling 22.8% conversion efficiency with an impressive fill factor of 81 % in two-sides contacted c-Si solar cells with passivating contacts using only 15 nm thick ITO layer
- Further optimization is required to reduce parasitic absorption in the TCO. One possibility would be to replace the ITO with indium free TCO as they are more thermally stable.

### Firing through process:

- Demonstration of a thick passivating contact deposited on front texturized surface in order to stop the silver paste
- Cell demonstrator enabling 19.4% conversion efficiency with a V<sub>OC</sub> of almost 700 mV and a fill factor of 78 %
- Currently, cells are limited by the absorption in the thick passivating contact. Localization of this contact is under study to develop high efficiency solar cells

## References

- [1] A. Richter *et al.*, Solmat, 2017  
 [2] F. Haase *et al.*, Jpn. J. Appl. Phys., 2017  
 [3] A. G. Aberle, PV Res. Appl., 2000  
 [4] B. Hallam *et al.* Phys. Status Solidi Appl. Mater. Sci., 2017  
 [5] F. Meyer *et al.* Solmat, to be submitted

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## Acknowledgement